

PATENT ASSIGNMENT

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CONVEYING PARTY DATA	
Name	Execution Date
The University of California	03/17/1995
RECEIVING PARTY DATA	
Name:	National Science Foundation
Street Address:	4201 Wilson Blvd
Internal Address:	Room 1265
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State/Country:	VIRGINIA
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PROPERTY NUMBERS Total: 1	
Property Type	Number
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LICENSE TO THE UNITED STATES GOVERNMENT

This instrument confirms to the United States Government, as represented by the National Science Foundation, an irrevocable, nonexclusive, nontransferable, royalty-free license to practice or have practiced on its behalf throughout the world the following subject invention:

Invention Title: QUANTUM DOT FABRICATION PROCESS USING STRAINED EPITAXIAL GROWTH

Inventors: Devin Leonard, Pierre Petroff, Mohan Krishnamurthy

Patent Application: QUANTUM DOT FABRICATION PROCESS USING STRAINED EPITAXIAL GROWTH

Serial Number: 08/330,303

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Country (if other than U.S.): Undetermined

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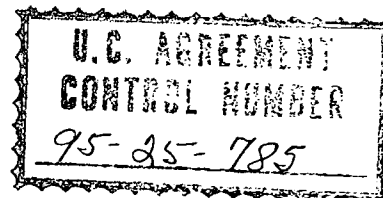
Principal rights to the subject invention have been left with The Regents of the University of California, Licensor.

Signed: Linda S. Stevenson
Name: Linda S. Stevenson
Title: Senior Prosecution Analyst,
Office of Technology Transfer

Date: March 17, 1995

Accepted on behalf of the Government: _____
NSF Patent Assistant

Date:



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